

ICP-MSを用いた気体試料の 直接分析



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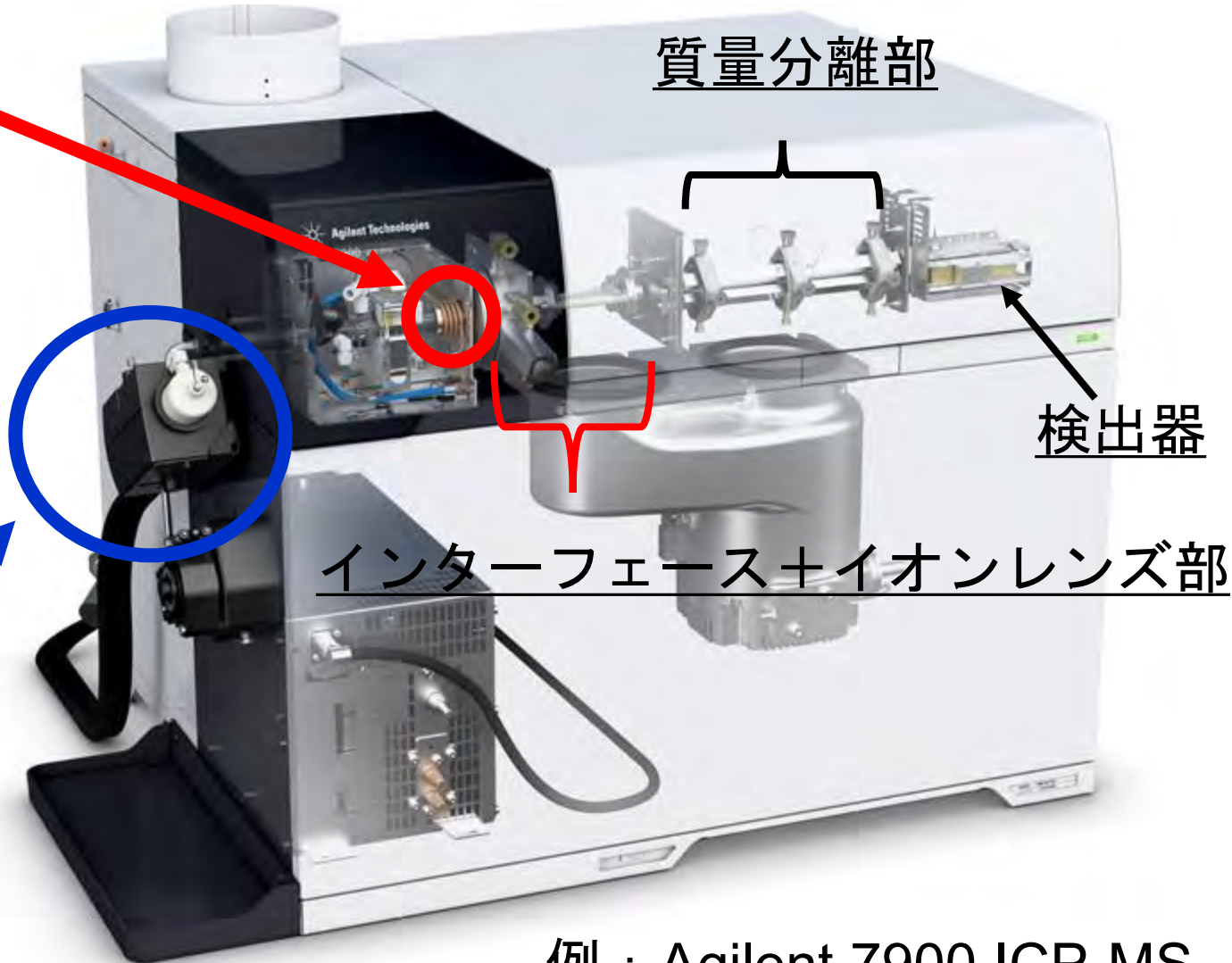
ICP-MS : 誘導結合プラズマ質量分析法

ICP-MS

- ・ 高感度元素分析法
- ・ 溶液試料測定が主流

ICP

ネブライザー
+ スプレーチャンバー



例 : Agilent 7900 ICP-MS

Direct multi-element analysis of SPM by GED-ICPMS

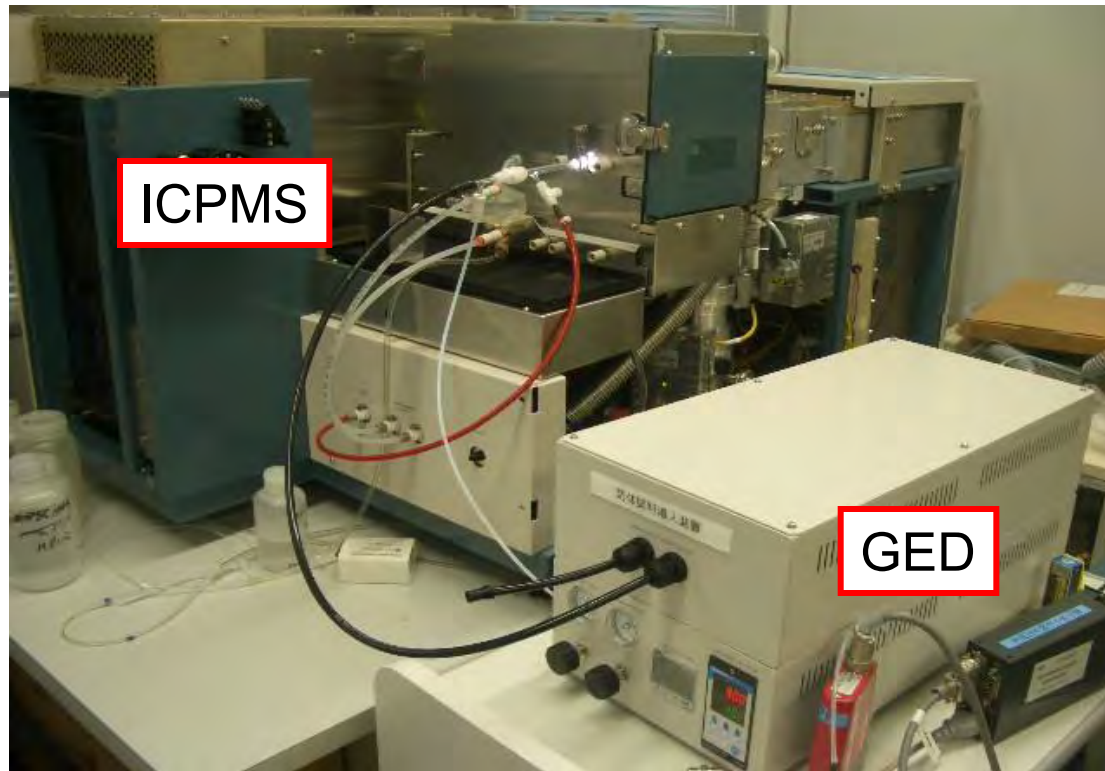
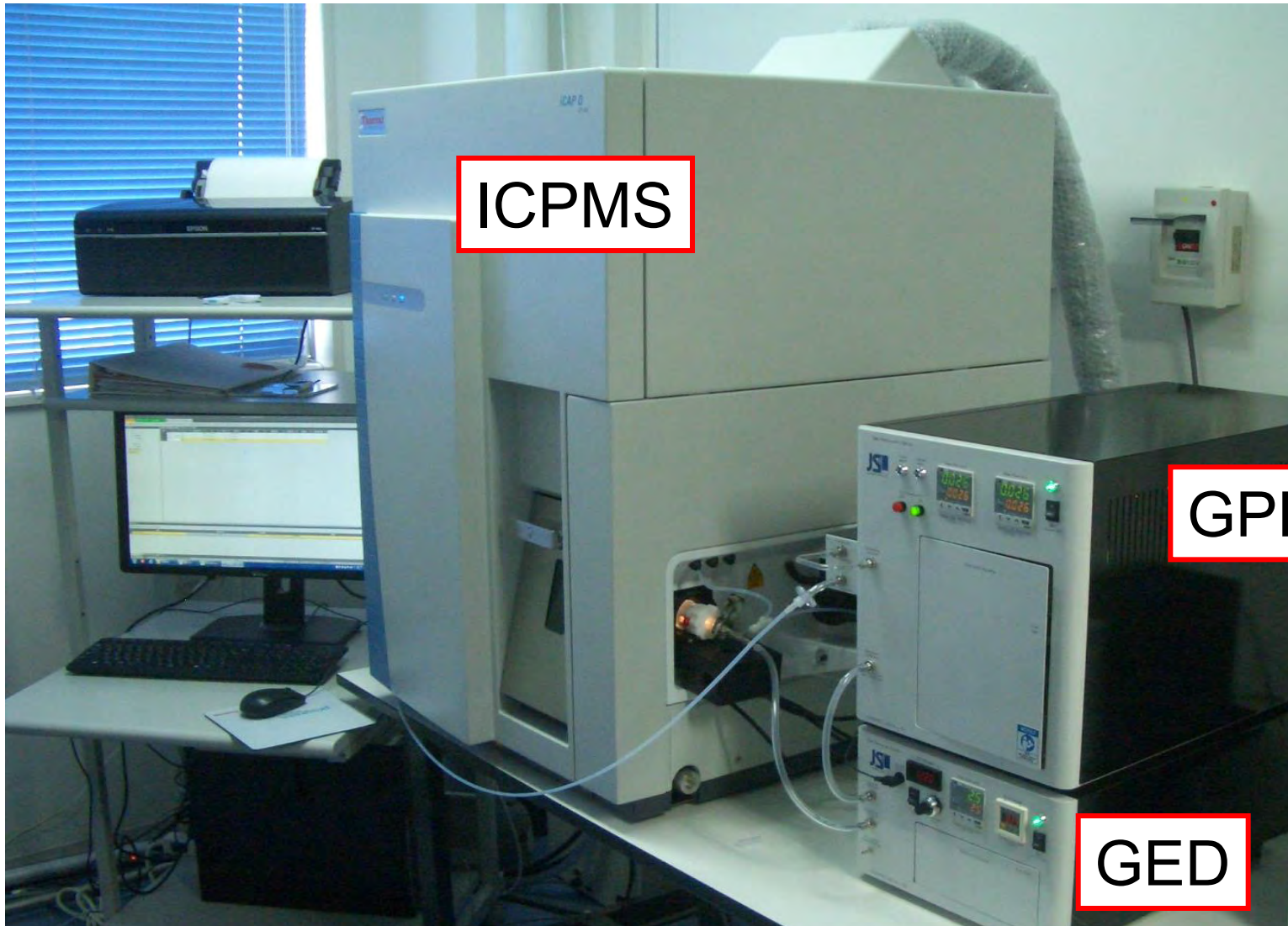


Photo of GPD-GED-ICPMS



気体試料の直接多元素分析

対象試料：

- ◎気体（希ガス、常温で気体状で存在する元素）
- ◎粒子（浮遊粒子状物質：SPM）


本分析手法の応用分野：

- ◎環境調査：大気環境モニタリング、局所環境（沿道など）調査、作業環境（室内など）調査など
- ◎燃焼煙調査：自動車排ガス、たばこ煙（主流煙、副流煙など）、排ガス（製造業、廃棄物処理施設など）、など
- ◎ガスおよびガスボンベ中の粒子分析（製品管理）、など

ICPMSを用いた気体試料の 直接多元素分析



① ガス交換・ICPMS法

 空気中の浮遊粒子状物質の元素分析

② 微粒子化・ガス交換・ICPMS法

 空気中の反応性ガスの分析

GED-ICPMS

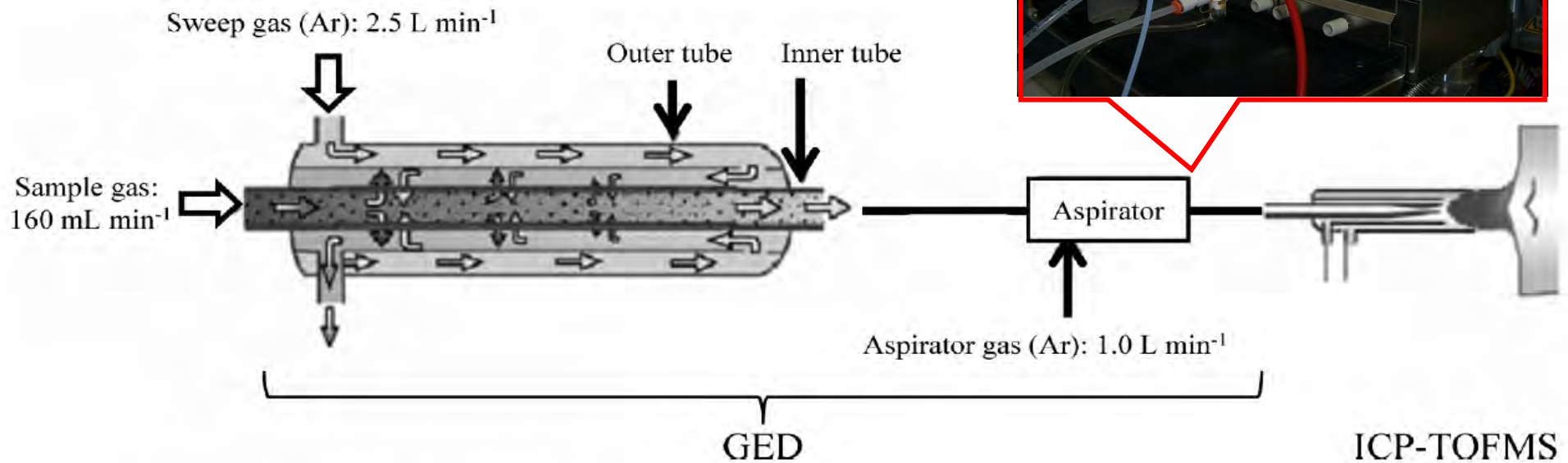


Fig. 1 Schematic diagram of GED-ICP-TOFMS

Specifications on glass film tube (inner tube) in GED are as followings: Name, Shirasu porous glass; Material, Porous silicate film; Pore size, 100 nm; Film porosity, 65 %; Thickness, 0.7–0.8 mm; Length, 700 mm (350 mm × 2); Outer diameter, 10 mm.

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Evolution on GED-ICPMS



住友化学 2008-I, 41-49

プラズマイオン源質量分析装置 を用いる気体試料直接分析法の 開発

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Development of Direct Analytical Method for Gaseous Samples by Plasma Source Mass Spectrometer

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Kohei NISHIGUCHI
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Real-time multielement monitoring of airborne particulate matter using ICP-MS instrument equipped with gas converter apparatus†‡

Kohei Nishiguchi,^a Keisuke Utani^a and Eiji Fujimori^{*b}

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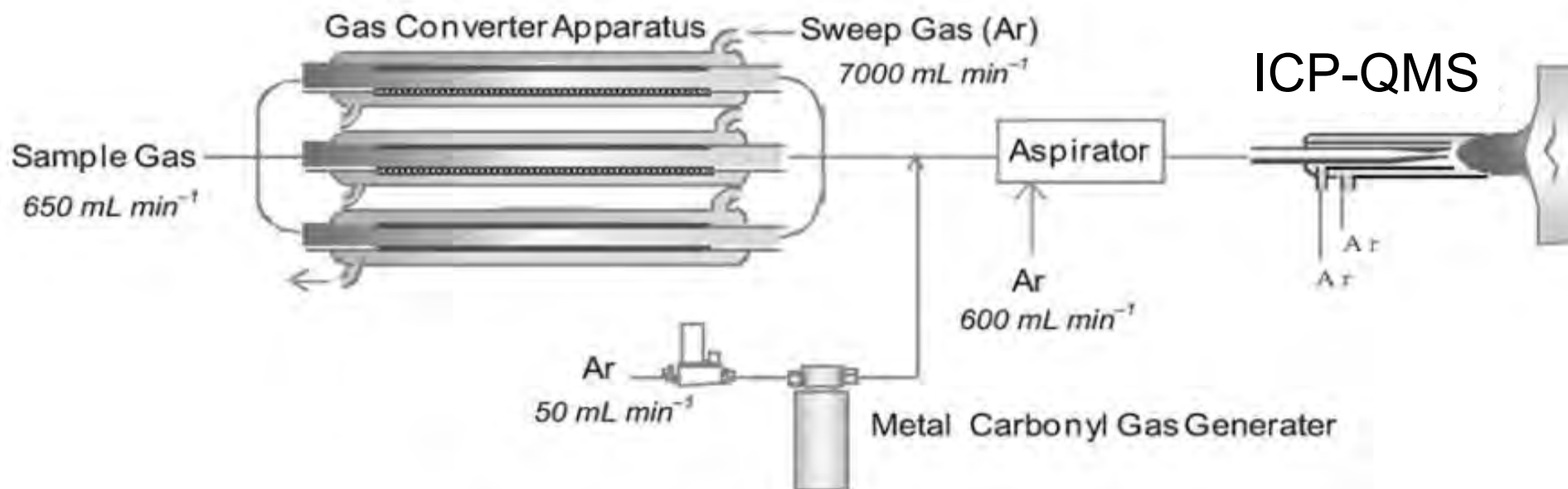


Fig. 2 Schematic diagram of gas converter/ICP-MS.

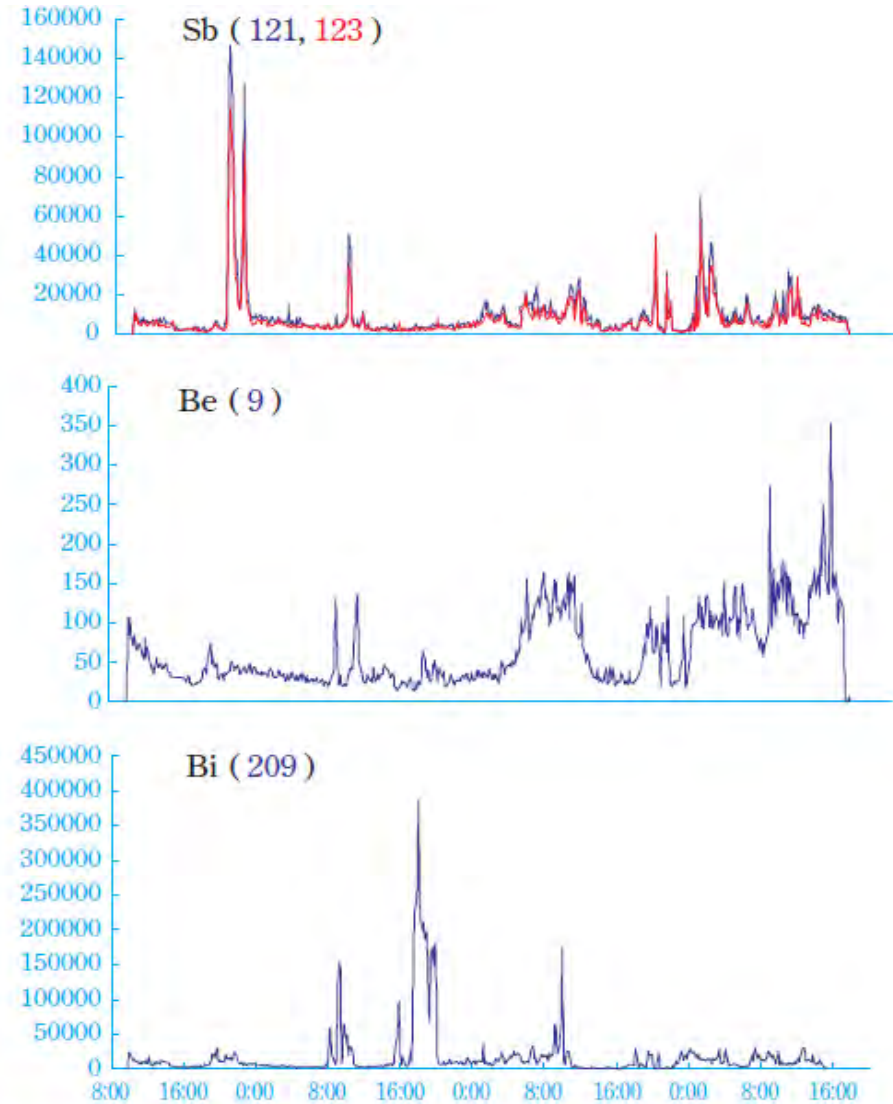
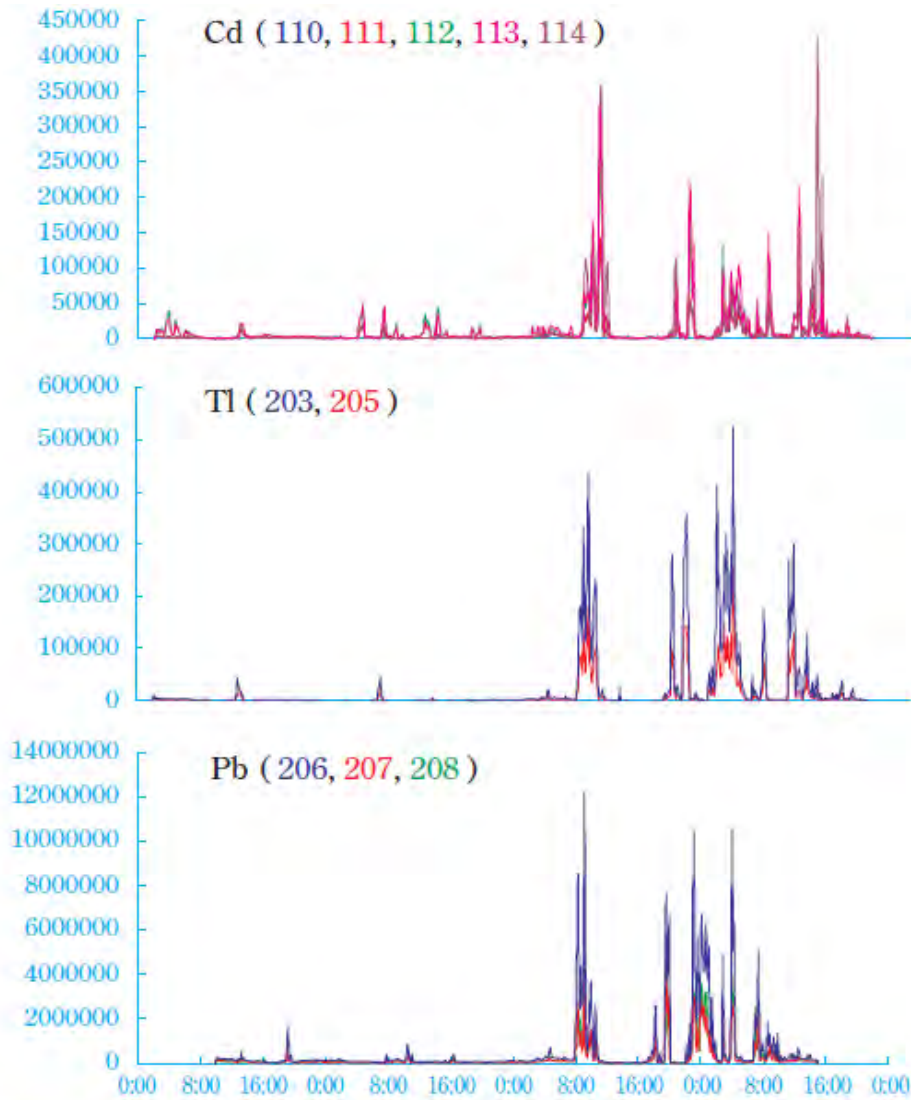


Fig. 15 Continuous Multielement Monitoring of Enviromental for 80 Hours

年間特集「空」：報 文

ガス交換/ICP-TOFMS によるたばこ煙の直接・多元素同時分析

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<Title in English>
Direct Simultaneous Multi-
element Analysis in
Tobacco Smoke by ICP-
TOFMS after Gas
Exchange

GED-ICP-TOFMS

ICP-TOFMS Spectrum Obtained by GED-ICP-TOFMS

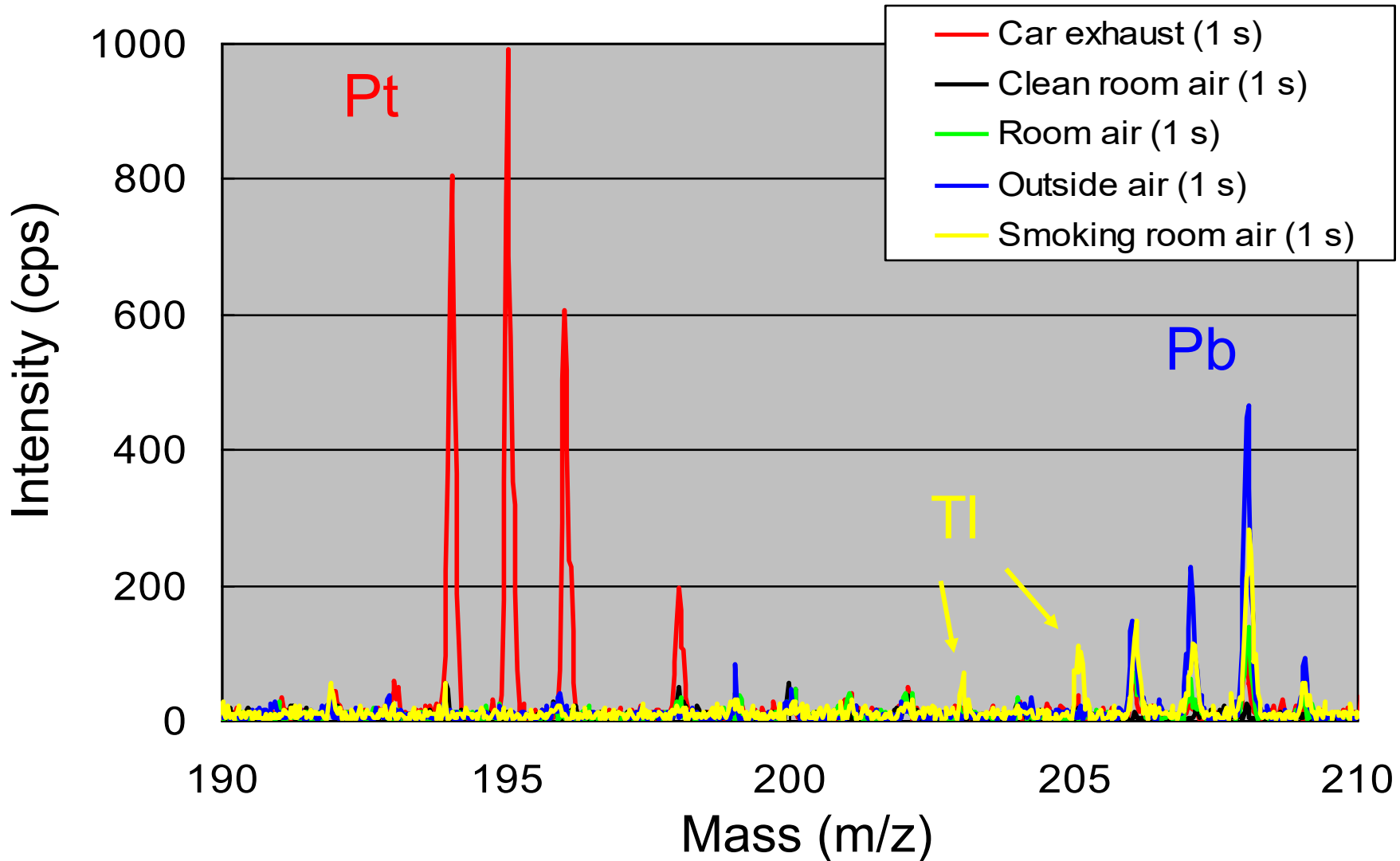
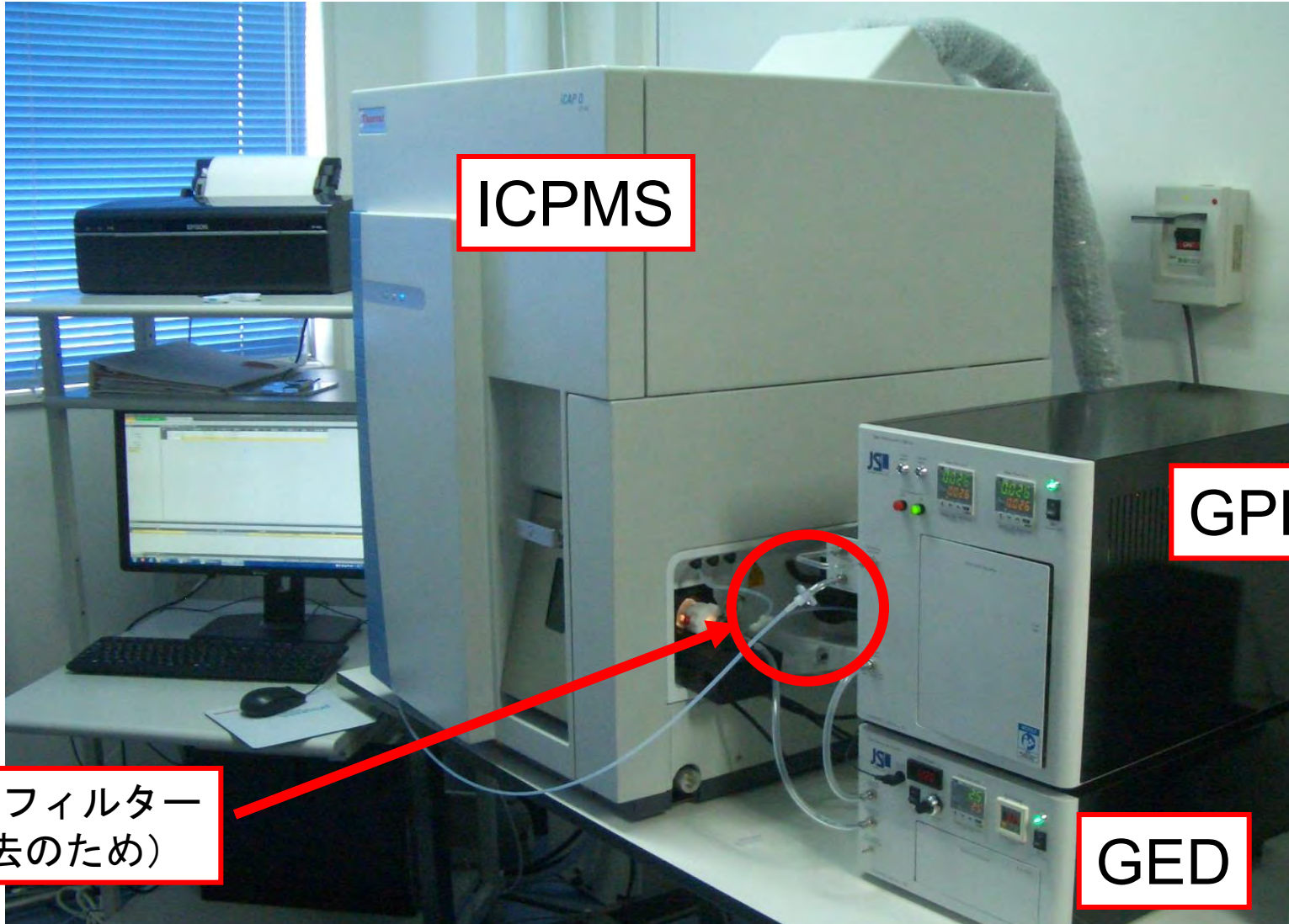
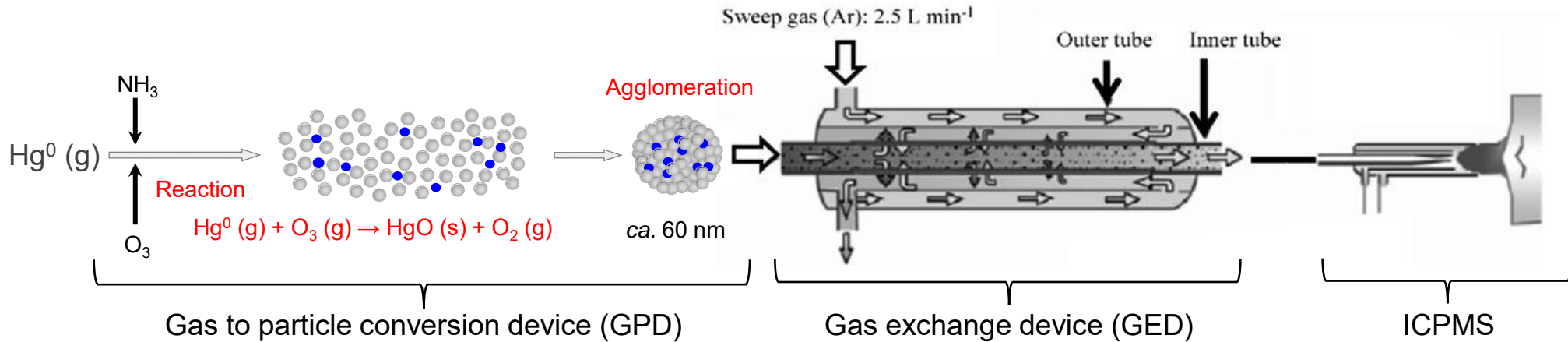
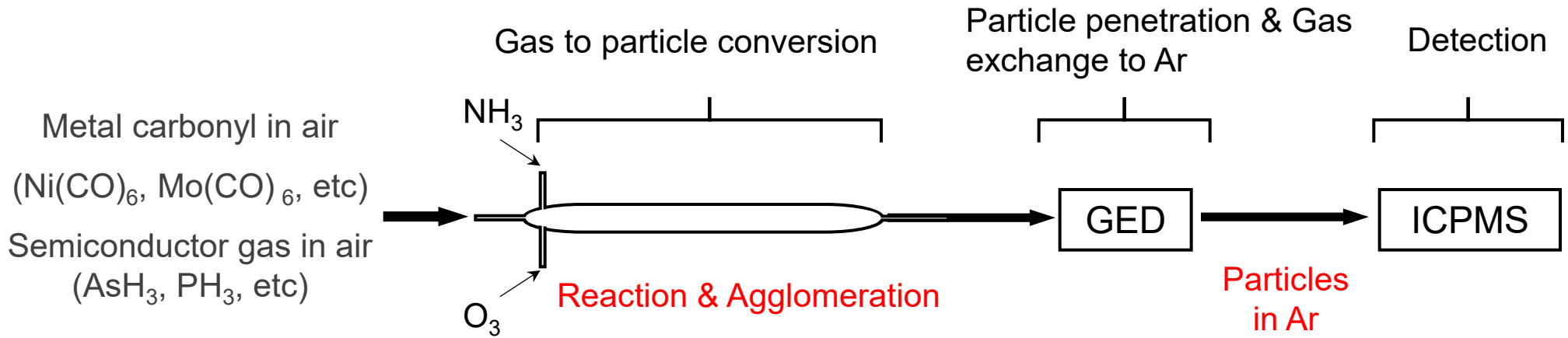


Photo of GPD-GED-ICPMS



GPD-GED-ICPMS



J. Anal. At. Spectrom., 2017, 32, 717–722

Analytica Chimica Acta 891 (2015) 73–78

Anal. Chem. 2014, 86, 10025–10029

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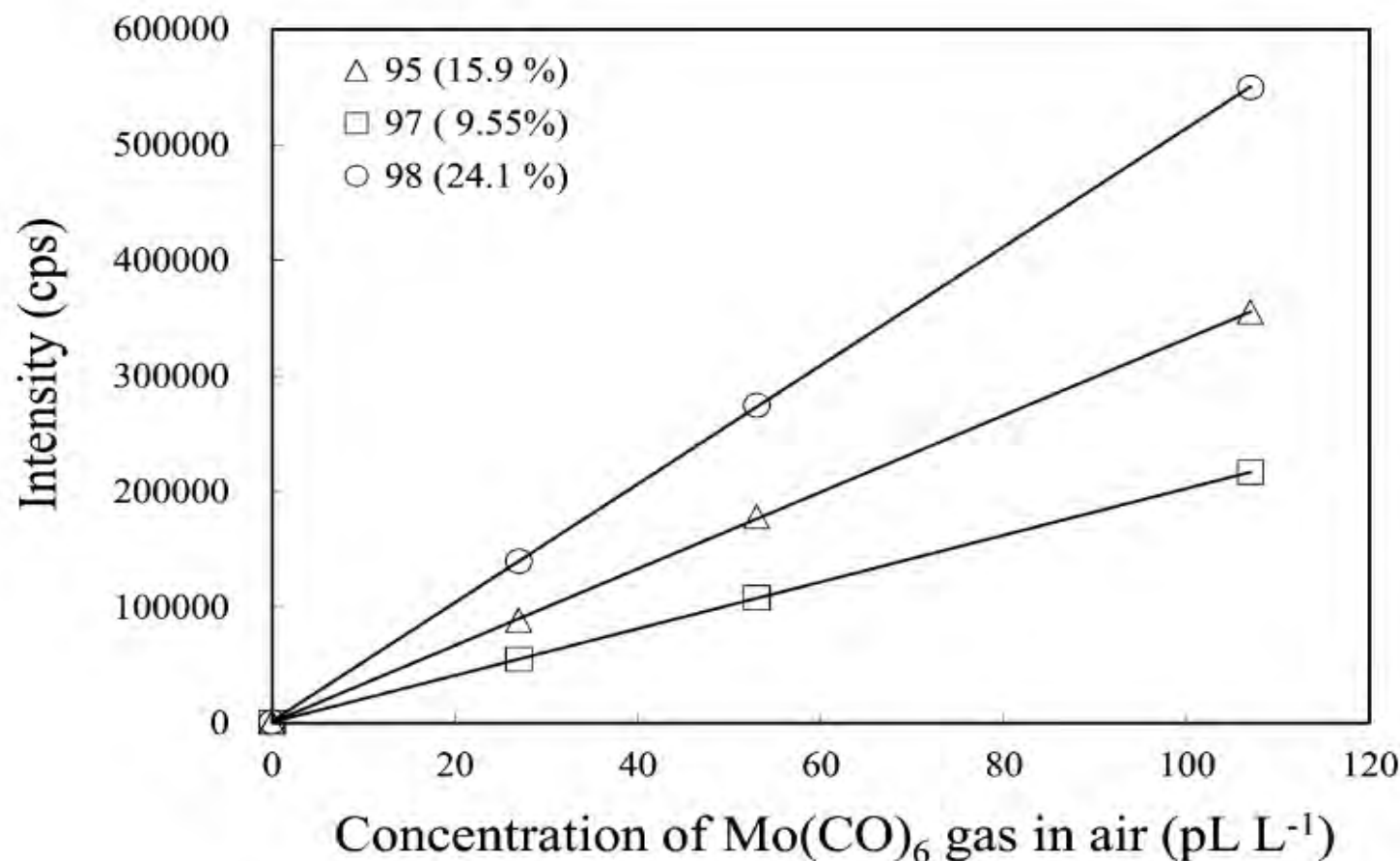
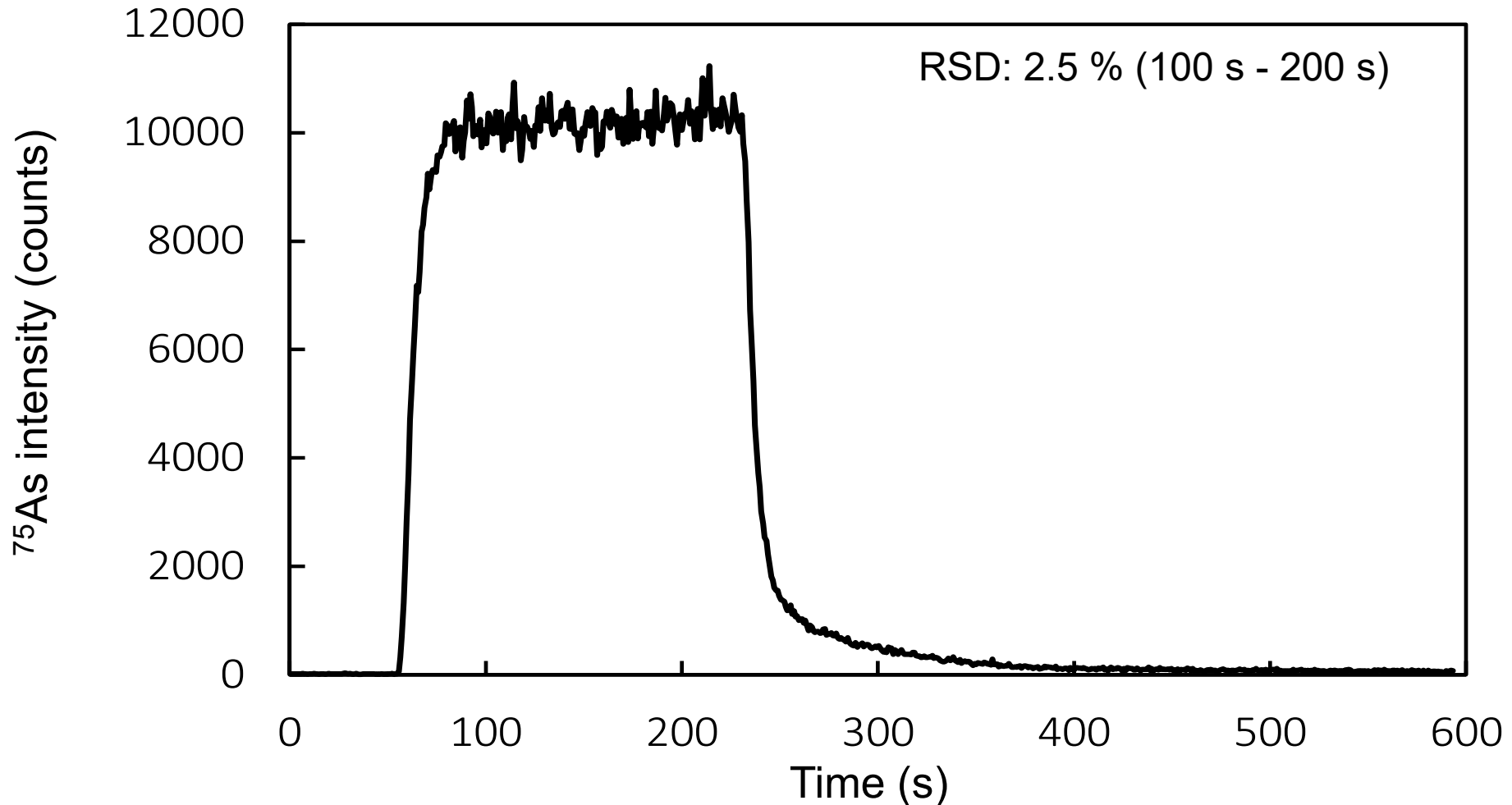


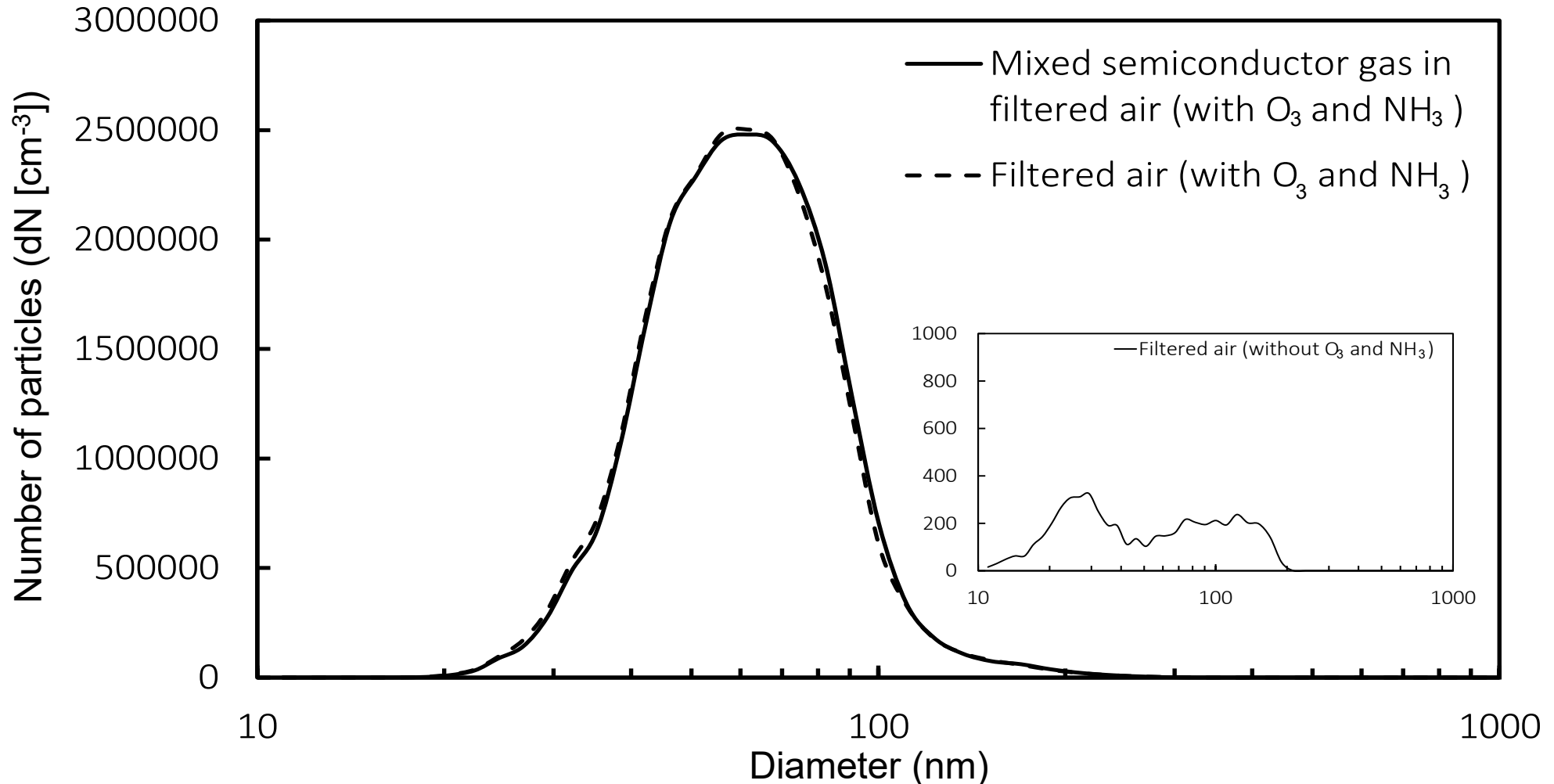
Figure 5. Calibration curves observed for different isotopes of Mo(CO)₆ by GPD-GEDICPMS. The flow rates of the sample gas introduction as well as 1% O₃ and NH₃ gases for GPD were 100 and 50 mL min⁻¹, respectively, and the concentration of the NH₃ solution was 4%.

Time-resolved signal of ^{75}As obtained by the introduction of 1 nL L $^{-1}$ AsH $_3$ in air through GPD-GED-ICPMS

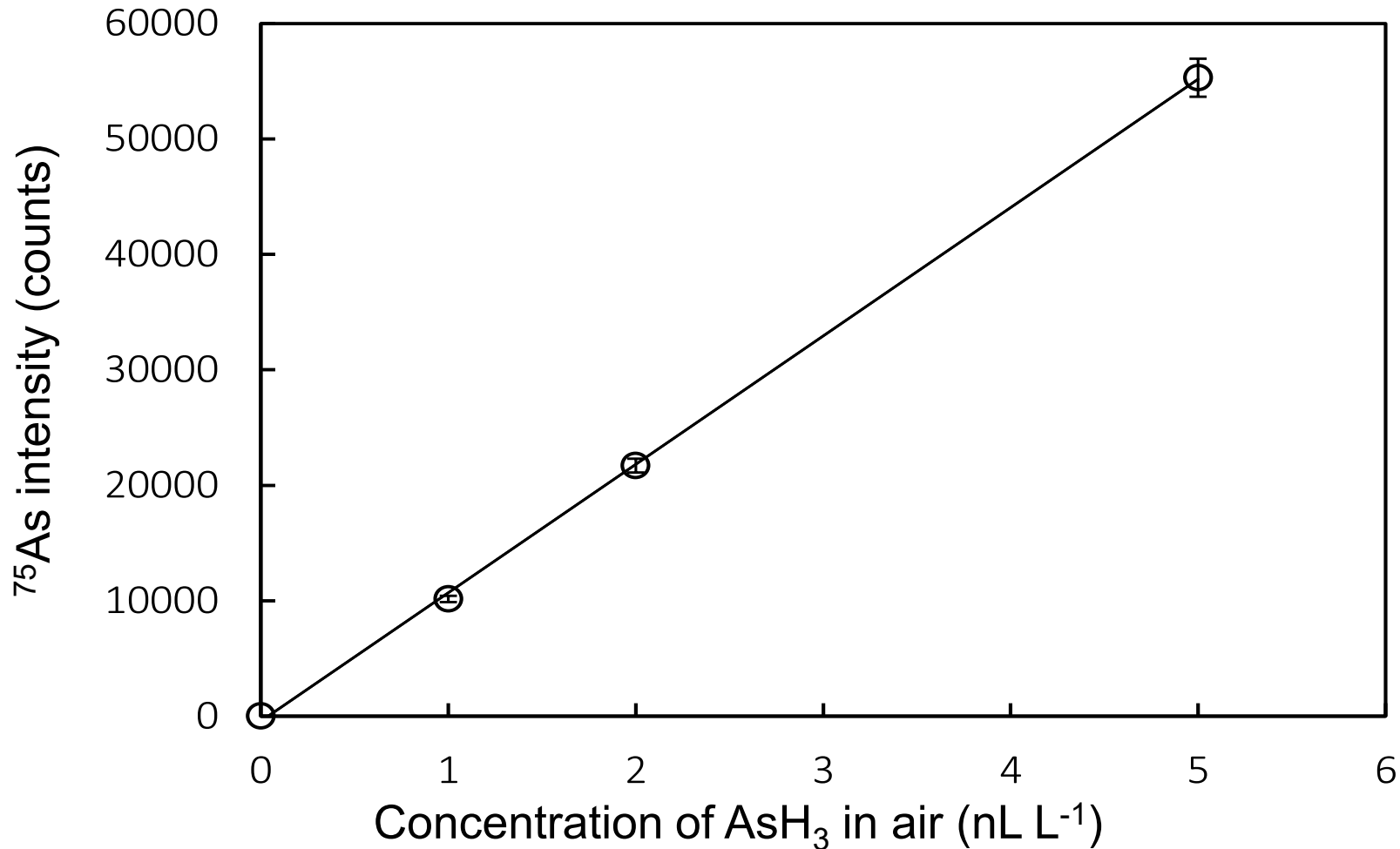


Size distribution of particles converted by gas to particle conversion device (GPD)

The mixed semiconductor gas: 1 nL L⁻¹ AsH₃ and PH₃ in air



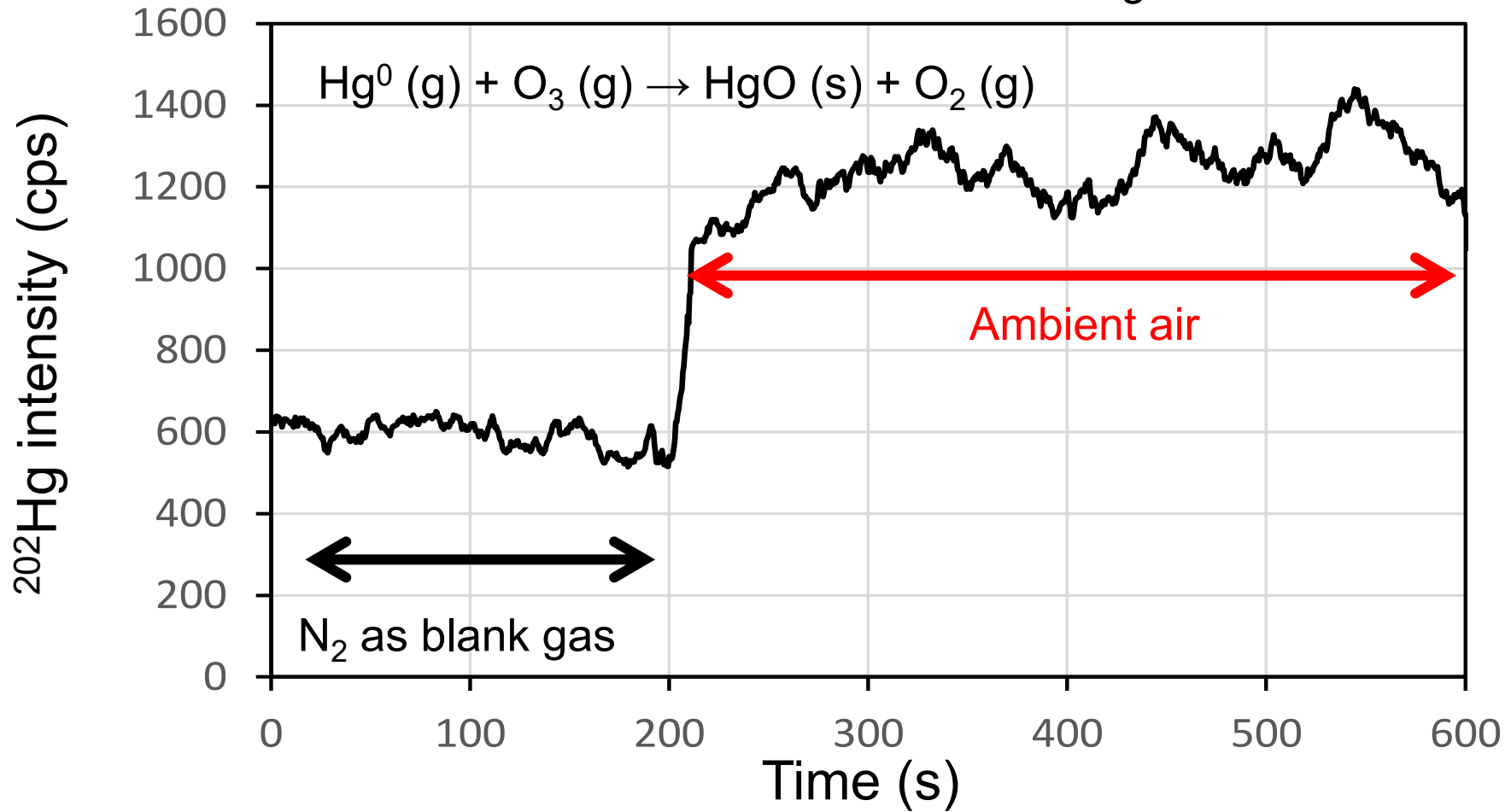
Calibration curve of ^{75}As obtained by GPD-GED-ICPMS for the introduction of AsH_3 in air



Time-resolved signal of ^{202}Hg from ambient air obtained by GPD-GED-ICPMS

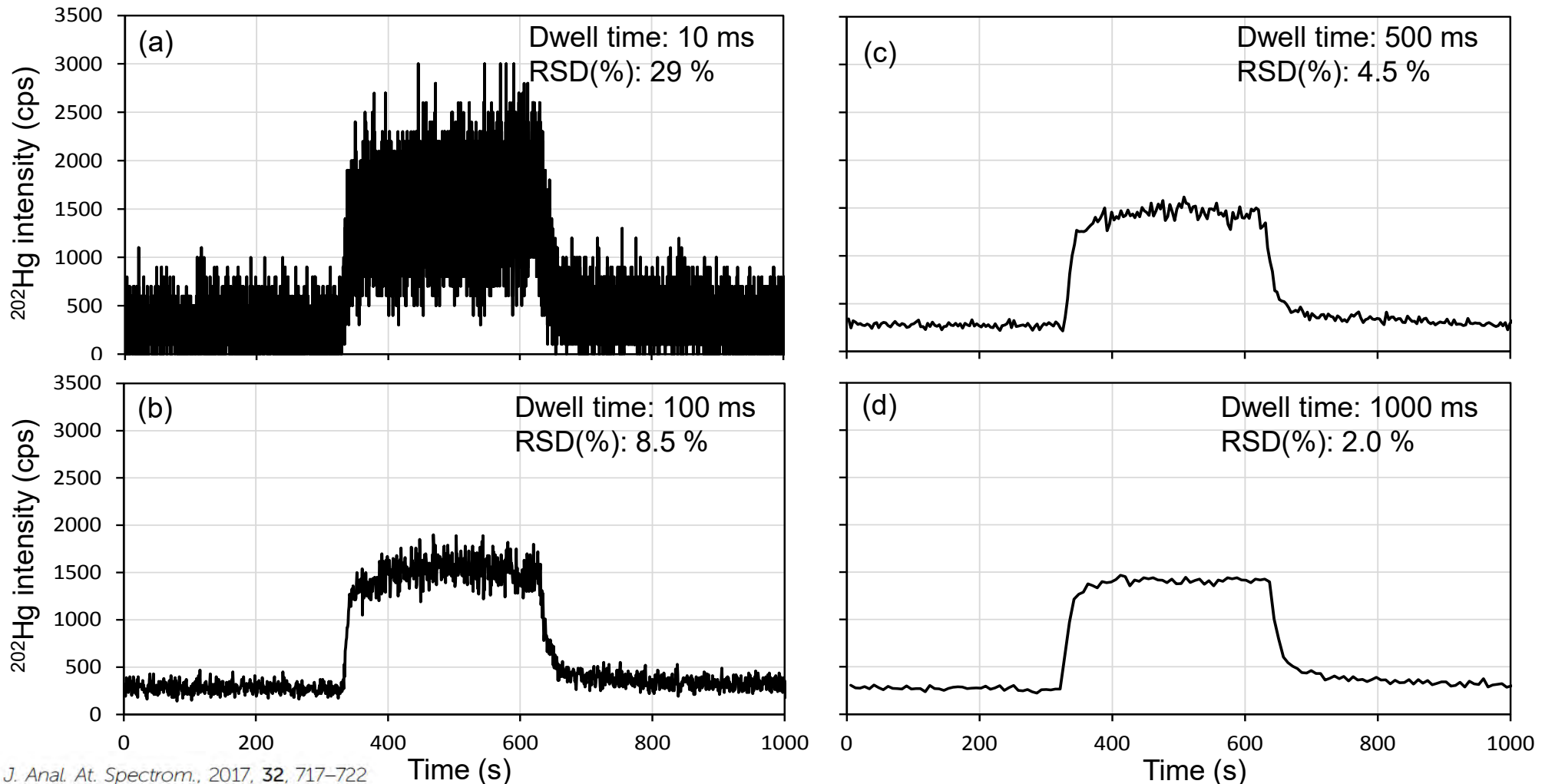
特開2017-198558

Integration time: 500 ms/data

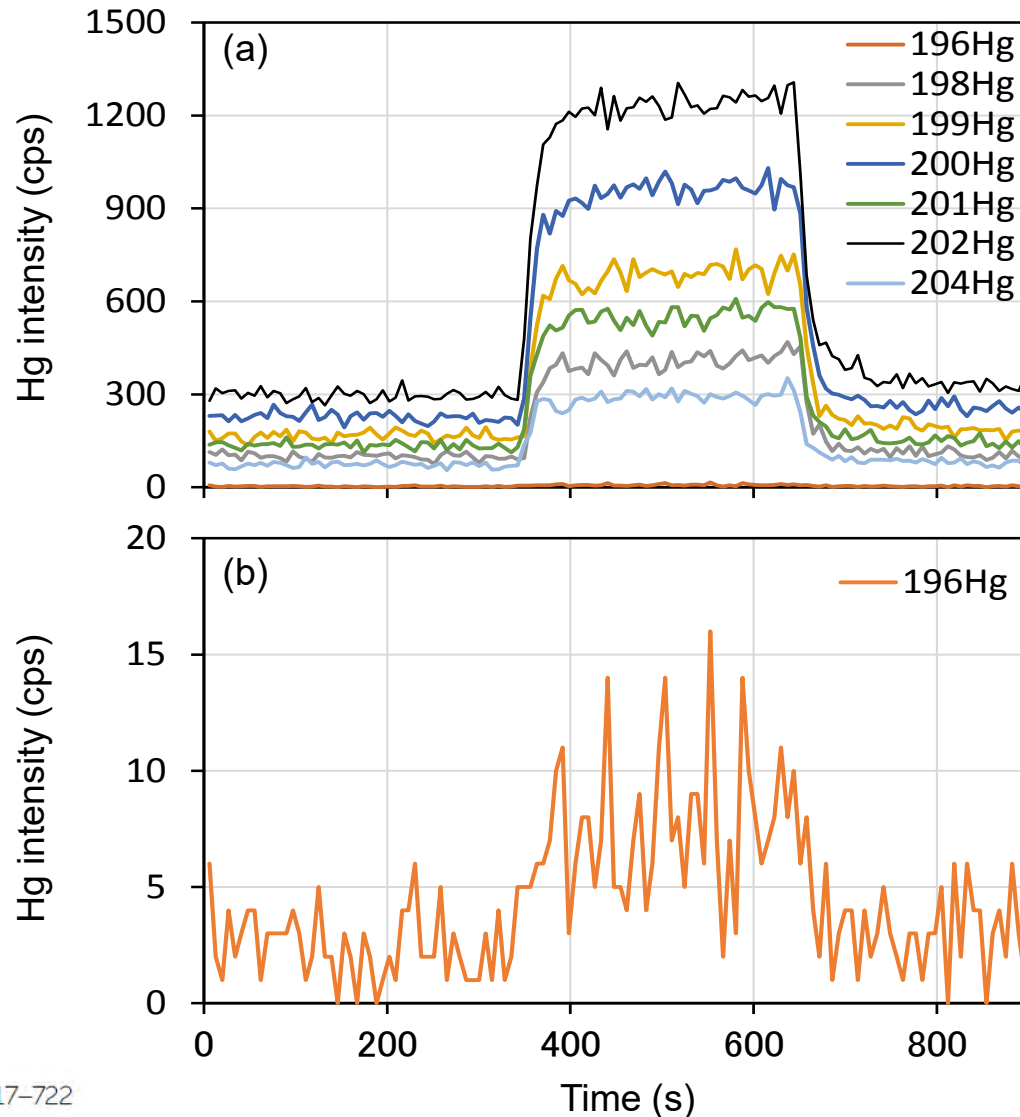


Time-resolved signal of ^{202}Hg from ambient air obtained by GPD-GED-ICPMS with different dwell times for ICPMS

The RSDs were calculated from the data obtained between 200 s and 400 s.



Time-resolved signals for (a) seven Hg isotopes and (b) ^{196}Hg from ambient air obtained by GPD-GED-ICPMS with 1000 ms of dwell time on ICPMS



Isotope abundances of gaseous Hg from ambient air obtained by GPD-GED-ICPMS without mass bias correction

	^{196}Hg	^{198}Hg	^{199}Hg	^{200}Hg	^{201}Hg	^{202}Hg	^{204}Hg
Gaseous Hg in ambient air	0.17 (0.03)	9.75 (0.07)	16.65 (0.30)	23.35 (0.24)	13.19 (0.16)	29.90 (0.13)	6.99 (0.08)
IUPAC value	0.15 [0.01]	9.97 [0.20]	16.87 [0.22]	23.10 [0.19]	13.18 [0.09]	29.86 [0.26]	6.87 [0.15]
Deviation (%) from IUPAC value	11	-2.2	-1.3	1.09	0.09	0.12	1.8

The value in parenthesis indicates 2SD from measurement.
The value in square bracket indicates estimated uncertainty.

Comparison of LODs (absolute amount) for gaseous Hg measurements (GEM or GEM + RGM)

CVAAS or CVAFS:

ca. 1 pg or *ca.* 0.1 pg, respectively

GPD-GED-ICPMS (GEM based estimation):

ca. 0.4 fg (@ 1s detection)

(0.12 ng m⁻³ @ 1 s measurement by 200 mL min⁻¹ sample introduction)